

## STALLMAN & POLLOCK LLP 353 Sacramento Street, Suite 2200 San Francisco, CA 94111 (415) 772-4900

In re Patent Application of: Michael Weber-Grabau et al.

Atty Docket No. TTI-31000 [TTI-328]

Application No.: 09/927,102

Filed: August 10, 2001

Confirmation No.: 3815

For:

OPTICAL CRITICAL DIMENSION METROLOGY SYSTEM INTEGRATED INTO

SEMICONDUCTOR WAFER PROCESS TOOL

M/S AMENDMENT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Transmittal herewith is an amendment in the above-identified application.

The fee has been calculated as shown below.

	CLAIMS		HIGHEST NO.	PRESENT	RATE	ADDITIONAL
E	REMAINING		PREVIOUSLY	EXTRA		FEE
	AFTER		PAID FOR			
	AMENDMENT					
TOTAL	12	MINUS	44	0	x \$50 =	\$0
INDEP.	3	MINUS	6	0	x \$200 =	\$0
FIRST PRE	SENTATION OF MU	+ \$360	\$0			
					TOTAL	\$0

Small Entity 50% Filing Fee Reduction (if applicable)

If the entry in Col. 1 is less than the entry in Col. 2, write "0" in Col. 3

If the "Highest Number Previously Paid For" IN THIS SPACE is less than 20, write "20" in this space. If the "Highest Number Previously Paid For" IN THIS SPACE is less than 3, write "3" in this space. The "Highest Number Previously Paid For" (Total or Independent is the highest number found from the equivalent box in Col. 1 of a prior amendment or the number of claims originally filed.)

1. 🛛 No additio	nal fee is required.
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A check in the amount of \$\_\_\_\_ is attached. 2.

 $\boxtimes$ Please charge any additional fees, including any fees necessary for extensions of time or credit 3. overpayment to Deposit Account No. 50-1703, under Order No. TTI-31000. A duplicate copy of this sheet is enclosed.

 $\boxtimes$ Petition for extension of time. The undersigned attorney of record hereby petitions for an 4. extension of time pursuant to 37 C.F.R. § 1.136(a), as may be required, to file this response.

STALLMAN & POLLOCK LLP

Dated: \_\_\_\_\_February 22, 2007

Michael J. Pollock

(Reg. No. 29,098)

\$0

Attorneys for Applicant(s)

## **CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on February 22, 2007

Dated: February 22, 2007



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Michael Weber-Grabau, et al.

Application No.: 09/927,102

Filed: August 10, 2001

For: CRITICAL DIMENSION METROLOGY

SYSTEM INTEGRATED INTO

SEMICONDUCTOR WAFER PROCESS

TOOL

Confirmation No.: 3815

Group Art Unit: 2877

Examiner: Richard A. Rosenberger

RESPONSE TO OFFICE ACTION MAILED NOVEMBER 24, 2006

353 Sacramento St., Suite 2200 San Francisco, CA 94111 (415) 772-4900

M/S AMENDMENT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 **CERTIFICATE OF MAILING** 

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STALLMAN & POLLOCK LLP

Dated: 02/22/2007

Georgie V/ Sti

Sir:

In response to the Office Action mailed November 24, 2006, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the Listing of Claims that begins on page 2 of this paper.

Remarks begin on page 6 of this paper.

Atty Docket No.: TTI-31000 [TTI-328]